

Abstract

Device for monitoring a lift area with a three-dimensional semiconductor sensor (79) for detecting three-dimensional image information. The semiconductor sensor (79) comprises a light source which is mounted so that the lift area to be monitored is disposed in the illuminated area of the light source, a sensor group which is mounted in such a manner that it receives reflected light, and a processing chip for converting the electrical signals into image information. In addition, the device comprises a processing device (80) which is connected with the semiconductor sensor (79) in order to make available three-dimensional image information. The processing device (80) processes the image information in order to obtain state information representing the state of the lift area to be monitored.

(Fig. 5A)